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## \*BIBDATASHEET\*

Bib Data Sheet

**CONFIRMATION NO. 6424** 

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SERIAL NUMBER 10/531,208	FILING OR 371(c) DATE 04/14/2005 RULE	CLASS 430		GROUP ART UNIT 1756		ATTORNEY DOCKET NO. 28955.1048				
APPLICANTS										
	Tokyo, JAPAN; Chiba, JAPAN;									
	TA ************************************		9/01/2003							
** FOREIGN APPLICATIONS ************************************										
JAPAN 2002300144 10/15/2002 JAPAN 2003112458 04/17/2003										
Foreign Priority claimed										
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35 USC 119 (a-d) condition	STATE OR COUNTRY		ETS WING	CLAIMS		CLAIMS				
Verified and JAPAN						20	)	3		
Acknowledged Examiner's Signature Initials ADDRESS										
27890										
TITLE										
Photoresist base material, method for purification thereof, and photoresist compositions										
						☐ All Fees				
					1.16 Fees (Filing)					
FILING FEE FEE	S: Authority has been given in Paperto charge/credit DEPOSIT ACCOUNTfor following:				☐ 1.17 Fees ( Processing Ext. of time )					
900 No.					6					
					1.18 Fees (Issue)					
				Other						
					☐ Credit					



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